MOOV

Request OEM Report

Notes:

Equipment impacted by a CDA event that allowed excessive moisture to enter the tool through the CDA supply line.

Equipment considered as parts sale only due to this.

CDA Lines showed water droplets at virtually all major and sensitive units.

Started purging at CDA source to stepper, and level of contamination was beyond initial thoughts.

CDA lines went from showing water droplets, to fully saturated.

After discovering water as more than just droplets in CDA lines & large amounts accumulated in low areas and near some fittings, decision to disassemble regulator & gauge panel.

CDA purging of individual lines went from sprays of water, to water flows & streams of water shooting from the piping when pressure applied.

Moisture absorbent pads were positioned around the stepper to contain the large amounts of water.

These large accumulations of water were found at the: regulator panel, wafer stage and damper distribution box, & at the Ulens purging distribution box.

Water was also found in the piping at the top of the chamber above the HEPA filters

For the most critical area, Ulens purging. Large amounts of water were found in piping.

All 4 lines to the Ulens contained water.

Cannon has no field procedure to determine what has entered the Ulens, but must make the assumption that with water in the piping to the Ulens purge, water is likely inside the Ulens.

Stepper will be reassembled, as Canon feels no further need to look for contamination at the CDA cooling supplied for the exposure shutter, masking blade unit, and illuminator.

Date of audit: 9/30/20025

Model

FPA-3030i5+
Wafer Size (inches)
6
Install Type: TTW / Stand-Alone
Stand-Alone
OEM MFG Date
2020
Install Date
2020
Is System On-Line?
NO
Off-Line Date (if applicable)
6/28/2024
Can Produce Wafers As-Is ?
NO
CE Mark Certified ?
YES
Are any Manuals included ?
Partial
OEM Audit Available?
YES
3rd Party Audit Available ?
NO
Decontamination Report Exists?
YES
Any Field Modifications ?
NO
All Cables present ?
YES
Any Corrosion visible on modules ?
YES
Any Missing / Damaged Parts ?
YES
Shipping Brackets Included ?
YES
Wafer Handler
YES
Handler Type
SiC Handling

# of Cassette / FOUP Loaders
Cassette Stage
Robot Type
OEM
End-Effecter Type
OEM
Pre-Aligner ?
YES
Mini-Environment
YES
Handler Options ?
SiC substrate
GEM / SECS ?
Yes
HSMS
Yes
Supporting Equipment
Std OEM items
CDA
N2
DIW
Chilled Water
Vacuum
Yes
Gas
NA
Power
200 3-phase 102A